



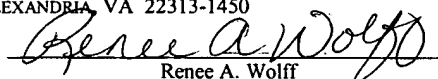
IFW

PATENT APPLICATION
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Oikari et al.	Examiner: Carrillo, Bibi Sharidan
Serial No.: 10/613,931	Group Art Unit: 1746
Filed: July 3, 2003	
For: WAFER PROCESSING USING GASEOUS ANTISTATIC AGENT DURING DRYING PHASE TO CONTROL CHARGE BUILD- UP	Docket No. FSI0111/US

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I CERTIFY THAT ON NOVEMBER 17, 2004, THIS PAPER IS BEING
DEPOSITED WITH THE U.S. POSTAL SERVICE AS FIRST CLASS MAIL IN
AN ENVELOPE ADDRESSED: COMMISSIONER FOR PATENTS, P.O. BOX
1450, ALEXANDRIA, VA 22313-1450


Renee A. Wolff

AMENDMENT

Dear Sir:

In response to the outstanding Official Action mailed August 17, 2004 please
amend the above-identified application as presented below.